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CONFIRMATION NO. 4274

Bib Data Sheet

SERIAL NUMBER 10/671,552	FILING DATE 09/29/2003  RULE	CLASS 438	GROUP ART UNIT 2812	ATTORNEY DOCKET NO. 8733.170.10	
<b>APPLICANTS</b>  Kwang Nam KIM, Kumi-shi, KOREA, REPUBLIC OF;  Gee Sung Chae, Incheon, KOREA, REPUBLIC OF;  <b>** CONTINUING DATA *****</b> AC This application is a DIV of 10/330,180 12/30/2002 PAT 6,716,752 AC which is a CON of 09/977,505 10/16/2001 PAT 6,627,545 AC which is a CON of 09/430,037 10/29/1999 PAT 6,337,292 AC  <b>** FOREIGN APPLICATIONS *****</b> JAPAN 1998-309237 10/29/1998 AC  <b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED</b> <b>** 12/19/2003</b>					
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged		STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 8	TOTAL CLAIMS 7	INDEPENDENT CLAIMS 1
<b>ADDRESS</b> MCKENNA LONG & ALDRIDGE LLP Song K. Jung 1900 K Street, N.W. Washington, DC 20006					
<b>TITLE</b> Method of forming silicon oxide layer and method of manufacturing thin film transistor thereby					
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